



SHEET 1 OF 1

Substitute for forms 1449A/PTO &amp; 1449B/PTO

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007413-056APPLICATION No.  
10/614,825APPLICANT  
Oliver KIENZLE et al.FILING DATE  
July 9, 2003GROUP  
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## U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
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## NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
JAV	Hansheng GUO et al., "Charging Phenomena and Charge Compensation in AES on Metal Oxides and Silica," SURFACE AND INTERFACE ANALYSIS, Vol. 25, pp. 390-396 (1997), John Wiley & Sons, Ltd.
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Examiner Signature	ZIA R. HASHMI	Date Considered	5/25/05
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